

Optics Letters

Temperature dependence mitigation in stationary Fourier-transform on-chip spectrometers

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Received 24 March 2017; revised 28 April 2017; accepted 28 April 2017; posted 4 May 2017 (Doc. ID 291293); published 0 MONTH 0000

We present two techniques for mitigating the effects of temperature drifts in waveguide spatial heterodyne Fourier-transform on-chip spectrometers. In high-resolution devices, large optical path length differences result in an increased sensitivity to temperature variations and impose stringent requirements on the thermal stabilization system. In order to overcome this limitation, here we experimentally demonstrate two new temperature mitigation techniques based on a temperature-sensitive calibration and phase error correction. The spectrometer chip under analysis comprises an array of 32 Mach-Zehnder interferometers fabricated on a silicon-on-insulator platform. The optical path delays are implemented as microphotonic spirals of linearly increasing length up to 3.779 cm, yielding a spectral resolution of 17 pm. We demonstrate that the degradation in retrieved spectra caused by temperature drift is effectively eliminated by temperature-sensitive calibration and phase error correction. © 2017 Optical Society of America

OCIS codes: (130.0130) Integrated optics; (300.0300) Spectroscopy.

<https://doi.org/10.1364/OL.99.099999>

Integrated spectrometers are sought after for a wide range of applications, such as optical communications, health diagnostics, biological and environmental sensing, and remote sensing from microsattellites [1,2], to name a few. Integrated spectrometers based on arrayed waveguide gratings [3], Bragg gratings [4], waveguide echelle and concave gratings [5,6], and cascaded microring resonators [7,8] can achieve subnanometer spectral resolutions and compact chip sizes. However, the optical throughput (*étendue*) of these devices is fundamentally limited by the need for a single-mode input waveguide. On the contrary, spatial heterodyne Fourier-transform (SHFT) spectrometers can provide a substantially larger *étendue* due to the possibility of multiple input waveguide apertures [9]. In an SHFT system, multiple interferometric measurements are performed in parallel using an array of interferometers, each with a

different optical path length difference (OPD) [10]. The input spectrum is calculated by the Fourier transform (FT) of the stationary spatial interferogram, which can be captured by a detector array in a single shot.

SHFT spectrometers have been successfully implemented on silicon-on-insulator (SOI) platforms [9]. The high refractive index contrast of SOI provides a high modal confinement with a correspondingly reduced bend radius, which ultimately allows a larger spectral resolution on a smaller chip footprint. The SHFT spectrometer can be implemented on an SOI platform as an array of N waveguide Mach-Zehnder interferometers (MZIs) [9]. In such a configuration, the spectral resolution ($\delta\lambda$) is determined by the OPD of the most unbalanced interferometer while the free spectral range (FSR) is set by the numbers of interferometers (N) [9,11]:

$$\delta\lambda = \frac{\lambda_0^2}{\Delta L_{\max} n_g}, \quad (1)$$

$$\text{FSR} = \delta\lambda \frac{N}{2}, \quad (2)$$

where λ_0 is the device central wavelength, ΔL_{\max} is the maximum MZI geometrical path difference, and n_g is the waveguide group index. For an arbitrary input signal, all the interferometer outputs (each corresponding to a different optical path difference) are measured simultaneously, resulting in a stationary wavelength-dependent spatial interferogram $I(\mathbf{x})_j$. The relation between the input spectral density $B(\bar{\sigma})$ and the output interferogram within the FSR of the device is given by [9]

$$I(x_i) = \int_0^{\text{FSR}} B(\bar{\sigma}) \cos(2\pi\bar{\sigma}x_i) d\bar{\sigma}, \quad (3)$$

where $\bar{\sigma} = \sigma - \sigma_L$ is the shifted wavenumber, relative to the Littrow wavenumber σ_L [12] at which maxima of the MZI responses are aligned, and x_i is the path delay of the i th MZI. This relation is unambiguous for an ideal device without phase errors, enabling the source spectrum to be retrieved by the Fourier cosine transform.

76 However, in fabricated devices, two main deviations from
77 the ideal behavior are present. Interferogram visibility variations
78 are produced by uneven propagation losses in waveguides
79 across the array. As the waveguide loss imbalance progressively
80 increases with optical path difference between the MZI arms
81 across the array, interferogram visibility is correspondingly re-
82 duced. This effect can be readily compensated by normalization
83 techniques [12]. Furthermore, fluctuations in fabricated wave-
84 guide properties, particularly the waveguide width, produce
85 fluctuations of the waveguide effective index, resulting in ran-
86 dom phase errors in the MZI transmittance functions.
87 Therefore, the phase alignment condition of the Littrow wave-
88 number and orthogonality of the FT transformation base are
89 not guaranteed, rendering Eq. (3) inadequate for practical spec-
90 tral retrieval.

91 To compensate for these errors, the use of active elements
92 (heaters) [11] was proposed. Alternatively, a fully passive spec-
93 tral retrieval algorithm based on a calibration matrix was devel-
94 oped [12]. Nevertheless, in order to ensure that the calibration
95 matrix is correctly implemented, MZI transmittance functions
96 must remain invariant between the calibration and the mea-
97 surement steps. The thermal dependence of Si-wire waveguides
98 hampers this requirement [13], as temperature variations
99 change the waveguide effective index and, therefore, the
100 OPD of each interferometer. This alters the MZI transmittance
101 functions, producing additional phase errors. For example, the
102 thermo-optic coefficients of Si-wire waveguides used in the
103 SHFT in [12], dn_{eff}/dT , are $1.8 \cdot 10^{-4} \text{ K}^{-1}$ and $1.2 \cdot$
104 10^{-4} K^{-1} for TE and TM polarizations, respectively, at a wave-
105 length of $1.55 \mu\text{m}$ [13]. Since the thermal-induced phase shift
106 increases with the interferometric delay, this imposes stringent
107 requirements on the thermal stabilization, particularly for de-
108 vices with high spectral resolution. Here we present two novel
109 spectral retrieval methods, based on temperature-sensitive cali-
110 bration and phase error correction to mitigate SHFT temper-
111 ature dependence. The technique is implemented on an SHFT
112 device with a resolution of 17 pm at a central wavelength of
113 1550 nm , with a compact footprint of 23 mm^2 .

114 Our first algorithm is based on the measurement of multiple
115 calibration matrices (C_j) of the same device at different tem-
116 peratures (T_j), followed by the automated selection of the ap-
117 propriate matrix for each particular spectral retrieval. The number
118 of required calibration matrices depends on the relation be-
119 tween the maximum temperature range for a specific applica-
120 tion and the minimum temperature change, which provides
121 correct spectral retrieval. The output interferogram can be ex-
122 pressed as $I(x_i, T_j, \lambda_k) = B(\lambda_k) \times C_j$, where λ_k are specific
123 wavelengths within the FSR of the device. In each calibration
124 matrix C_j , the transmittance function of each MZI is sampled
125 at M typically equidistant wavelengths with a narrowband tun-
126 able laser within the FSR of the device. Each matrix hence com-
127 prises N rows, which represent the normalized power of the
128 output interferogram for each wavelength, and M columns,
129 corresponding to the spectral response of each MZI. In an ideal
130 scenario, the source spectrum can be obtained by multiplying
131 the interferogram by the inverse of the transformation matrix.
132 When the transformation base is not orthogonal (e.g., in the
133 presence of phase errors), the calibration matrix is not invertible
134 and its pseudoinverse is used instead.

135 For the correct selection of the temperature-dependent
136 calibration matrix, an auxiliary temperature measurement is

137 required. This step can be directly performed with a high-prec-
138 ision measurement of the chip temperature (T_{aux}). The cali-
139 bration matrix selected for the spectral retrieval algorithm is
140 then the matrix, C_j , obtained at the temperature T_j nearest
141 to T_{aux} . Alternatively, the output interferogram (I_{aux}) of a
142 reference input signal with a known spectrum (B_{ref}) can be
143 used for accurate temperature determination. In this case,
144 the appropriate calibration matrix is selected by minimizing
145 the following expression:

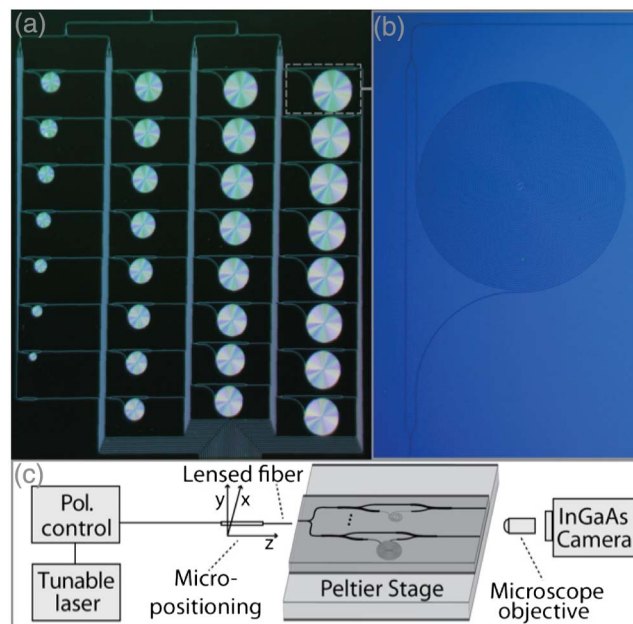
$$\sum_{i=1}^N |I_{\text{aux}} - B_{\text{ref}} \times C_j|. \quad (4)$$

146 Our second algorithm utilizes amplitude and phase error
147 correction for narrowband signals. Each MZI's transmittance
148 function in the calibration matrix is (mathematically) normal-
149 ized, shifted, and aligned, obtaining an aligned matrix C'_j and a
150 phase shift vector $\Delta\lambda$:

$$C'_j(x_i, \lambda_k) = C_j(x_i, \lambda_k - \Delta\lambda(x_i)). \quad (5)$$

151 By applying this vector to the output interferogram to be
152 analyzed, a corrected interferogram $I'(\mathbf{x})_j$ with improved or-
153 thogonality and the Littrow condition is obtained. An indeter-
154 mination arises when applying $\Delta\lambda$, as a given signal level can
155 correspond to either a rising or descending flank of the MZI
156 transmittance function. This issue can be solved in the particu-
157 lar case of narrowband input spectra by measuring the output
158 interferogram at two close temperatures (T and $T + \Delta T$). By
159 analyzing the effect of small temperature changes in the output
160 signal levels, the indetermination is resolved.

161 Both algorithms were demonstrated on an SHFT micro-
162 spectrometer comprising an array of 32 silicon waveguide
163 MZIs with a reference straight arm of constant length and a
164 microphotonic spiral arm with linearly increasing length
165 (Fig. 1). The high index contrast of the SOI platform enables



166 **Fig. 1.** (a) Optical micrograph of the fabricated spatial heterodyne
167 Fourier-transform spectrometer chip with spiral silicon wire wave-
168 guides, and (b) details of the most unbalanced Mach-Zehnder inter-
169 ferometer. (c) Schematic description of the measurement setup.

F1:1
F1:2
F1:3
F1:4

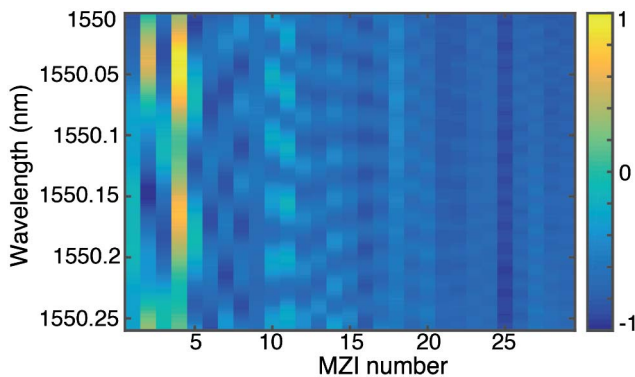
166 fabrication of tightly coiled spirals. Here we implemented a
 167 maximum length difference of 3.779 cm in a spiral diameter
 168 of only 490 μm . To ensure single-mode operation and negli-
 169 gible bend losses, 450 nm wide \times 260 nm thick Si-wire wave-
 170 guides with a minimum bend radius of 5 μm were used.
 171 Propagation losses of -4 dB/cm were measured, with bending
 172 losses of -1.7 dB/cm in the spiral sections.

173 These design parameters result in a theoretical spectral resolu-
 174 tion of 14.5 pm and an FSR of 0.23 nm in a compact device
 175 footprint of 23 mm^2 . Efficient subwavelength grating edge
 176 couplers [14] integrated on the chip were used for fiber-chip
 177 coupling, while at the same time reducing the Fabry–Perot
 178 effect by minimizing the reflectivity at the facets.

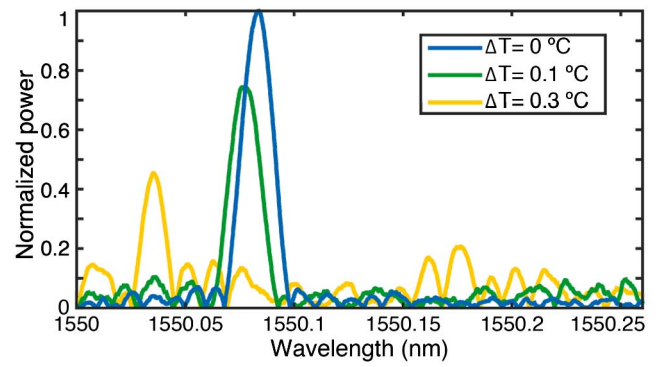
179 The device was fabricated on SOI wafers with 260 nm thick
 180 silicon and 2 μm buried oxide. The waveguides were defined in
 181 a single patterning step by electron beam lithography using
 182 hydrogen silsesquioxane resist. Inductively coupled plasma
 183 reactive ion etching was used to transfer the resist pattern into
 184 the silicon layer.

185 The fabricated device was characterized using a high-
 186 resolution tunable semiconductor laser over the spectral range
 187 of 1550–1550.6 nm, with a wavelength step of 0.5 pm. A
 188 Peltier stage was used for thermal stabilization of the chip,
 189 and a TE-polarization state was selected through an external
 190 polarization controller [Fig. 1(c)]. Output light from the
 191 MZIs was collimated by a microscope objective and captured
 192 in a single shot with a high-sensitivity InGaAs camera.

193 For the microspectrometer under analysis, the TE-
 194 polarization calibration matrix was measured at three different
 195 temperatures ($T_1 = 22.4^\circ\text{C}$, $T_2 = 22.5^\circ\text{C}$, and $T_3 = 22.7^\circ\text{C}$).
 196 Room temperature was maintained at 22.4°C . The responses
 197 of three interferometers (24, 27, and 32) were removed from
 198 the matrix due to a low signal-to-noise ratio caused by some de-
 199 fective waveguides. Due to the exclusion of the last MZI (#32,
 200 with the maximum imbalance), the maximum length difference
 201 is reduced to 3.658 cm, leading to a theoretical resolution of
 202 15 pm. A revised theoretical FSR of 0.22 nm is estimated for
 203 this set of 29 interferometers. Figure 2 shows the calibration
 204 maps for these three specific temperatures, without amplitude
 205 or phase corrections. The visibility reduction can be observed
 206 along the horizontal axis (MZI number), while along the vertical
 207 axis (wavelength) the misalignments of the transmittance func-
 208 tions of different MZIs due to phase errors are noticed.



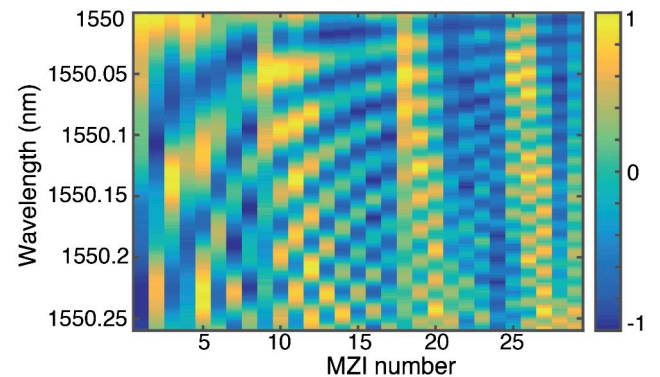
F2:1 **Fig. 2.** Experimental characterization of the spectral response of
 F2:2 each interferometer in a 0.26 nm FSR for three different temperatures
 F2:3 ($T_1 < T_2 < T_3$).



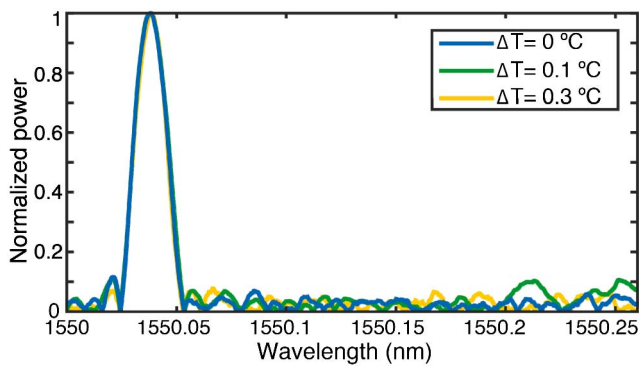
F3:1 **Fig. 3.** Spectral retrievals of a first monochromatic input signal measured at 22.4°C , demonstrating the degradation caused by temperature
 F3:2 mismatches (ΔT) between said measurement temperature and the calibration
 F3:3 temperature.
 F3:4

209 In Fig. 3, we show a first experimental spectral retrieval of a
 210 monochromatic signal measured at $T = 22.4^\circ\text{C}$ after selecting the
 211 appropriate matrix calibrated at the same temperature ($\Delta T = 0^\circ\text{C}$),
 212 as well as for several uncorrected temperature mismatches ($\Delta T = 0.1^\circ\text{C}$,
 213 $\Delta T = 0.3^\circ\text{C}$) between calibration and measurement steps. Temper-
 214 ature changes modify the OPD of each interferometer differently. Therefore,
 215 a length-dependent displacement of the MZI transmittance functions is
 216 produced. As a consequence, the central wavelength is shifted and the
 217 sidelobe level increases with the temperature difference.
 218 A 6 pm central-wavelength displacement is measured for $\Delta T = 0.1^\circ\text{C}$,
 219 which corresponds to a 180° phase shift in the output of the longest
 220 MZI in the particular device herein described. Significant spectral
 221 retrieval deterioration is already found for $\Delta T = 0.3^\circ\text{C}$. The relation
 222 between ΔT and the described output interferogram changes is
 223 proportional to device resolution. An experimental resolution of 17
 224 pm in an FSR of 0.26 nm is demonstrated. This result verifies the
 225 circumvention of the stringent temperature control requirements associ-
 226 ated with this resolution in previous retrieval algorithms.
 227

228 Second, in order to correct the nonorthogonality of the
 229 Fourier base (phase errors) and the visibility losses (amplitude
 230 errors), all the MZI functions in each experimental calibration
 231



F4:1 **Fig. 4.** Calibration map for a temperature of 22.4°C after alignment
 F4:2 and shifting of the MZI transmittance functions and normalization.
 F4:3 The Littrow condition holds at a wavelength $\lambda_L = 1550$ nm where
 F4:4 the transmittance functions of all MZIs are in-phase.



F5:1 **Fig. 5.** Spectral retrievals of a second monochromatic input signal
 F5:2 using the calibration-based spectral retrieval algorithm after phase and
 F5:3 amplitude corrections.

232 matrix were normalized and aligned to the Littrow wavelength
 233 of 1550 nm. The resulting calibration map for a temperature of
 234 22.4°C is shown in Fig. 4. The temperature-dependent phase
 235 shift vector, $\Delta\lambda$, was then used to correct the phase errors in the
 236 measured interferograms.

237 Using both of our methods simultaneously, that is selecting
 238 the specific calibration matrix and correcting both the phase
 239 and amplitude errors, the effects of temperature dependence
 240 are compensated and corrected, yielding athermal device behav-
 241 ior. As shown in Fig. 5, the spectral retrieval of a monochro-
 242 matic source is substantially improved by combining both
 243 methods.

244 In this work, we presented two techniques for compensating
 245 the effects of thermal changes in a spatial heterodyne Fourier-
 246 transform spectrometer, namely, temperature-dependent
 247 calibration matrices and numerical reconstruction of the
 248 Littrow condition. These techniques were experimentally
 249 implemented on an SHFT device fabricated on an SOI plat-
 250 form. The spectrometer comprises an array of 32 waveguide
 251 Mach–Zehnder interferometers with a linearly increasing
 252 imbalance across the array, up to 3.779 cm. Spectral retrieval
 253 degradation effects caused by the temperature difference be-
 254 tween the calibration and the actual spectral measurement were
 255 characterized and corrected. A spectral resolution of 17 pm in a
 256 0.22 nm free spectral range was experimentally demonstrated.
 257 These results pave the way for the development of athermal
 258 high-resolution integrated spectrometers combining hardware

and software athermalization techniques for diverse applica- 259
 tions ranging from handheld to microsatellite on-chip 260
 spectroscopy. 261

Funding. Ministerio de Economía y Competitividad **1** 262
 (MINECO) (FJCI-2014-22836, TEC2015-71127-C2-1-R, 263
 TEC2015-71127-C2-2-R); Comunidad de Madrid (S2013/ 264
 MIT-2790); EURAMET (H2020-MSCA-RISE-2016: 265
 SENSIBLE); EMPIR Programme (JRP-12-2014-IND13- 266
 PhotInd); National Research Council Canada (NRC); 267
 European Union's Horizon 2020 Research and Innovation 268
 Programme under Marie Skłodowska-Curie grant (734331). 269

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Queries

- 304 1. AU: The funding information for this article has been generated using the information you provided to OSA at the time of article submission. Please check it carefully. If any information needs to be corrected or added, please provide the full name of the funding organization/institution as provided in the CrossRef Open Funder Registry (<http://www.crossref.org/fundingdata/registry.html>).